

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

<p>In re Application Inventor(s): Tue Nguyen et al. Appln. No.: 09/898,439 Confirm. No.: 1885 Filed: July 5, 2001 Title: PLASMA SEMICONDUCTOR PROCESSING SYSTEM AND METHOD</p>	<p><b>PATENT APPLICATION</b></p> <p>Art Unit: 2818 Examiner: Hoang, Quoc Dinh</p> <p><b><u>Customer No. 23910</u></b></p>
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**CERTIFICATE OF MAILING UNDER 37 C.F.R. § 1.8**

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(Attorney Signature)

Sheldon R. Meyer, Reg. No. 27,660

Signature Date: 10/19/2004

**RESPONSE TO OFFICE ACTION UNDER 37 C.F.R. § 1.111**

Commissioner for Patents  
P.O. Box 1450  
Art Unit 2818  
Alexandria, VA 22313-1450

Sir:

**AMENDMENTS**

This Response is in reply to the First Office Action July 14, 2004, setting a three-month period for response. This response therefore is timely.

**Amendments to the Specification** begin on page 2 of this paper.

**Amendments to the Claims** begin on page 3 of this paper.

**Remarks/Arguments** begin on page 9 of this paper.

Please amend the above-identified application as follows: